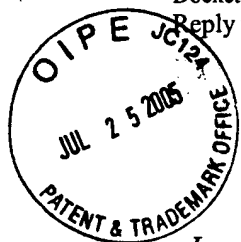


Appl. No.: 10/029,158  
Amdt. dated July 22, 2005  
Docket No.: A-69175-1/MSS (463035-650)  
Reply to Office Action of March 22, 2005



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

*In re* application of:

**Nam P. Suh et al.**

Serial No.: **10/029,158**

Filed: **December 21, 2001**

For: **APPARATUS AND METHOD FOR  
CHEMICAL MECHANICAL  
POLISHING OF SUBSTRATES**

Examiner: **RACHUBA, Maurina T.**

Art Unit: **3723**

Confirmation No.: **5210**

San Francisco, CA **94111**

Date: **July 22, 2005**

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Alexandria, VA 22313-1450

**AMENDMENT/RESPONSE**

Sir:

In response to the final Office Action mailed March 22, 2005, Applicants submit the following amendments and remarks. A petition for a one-month extension of time with the requisite deposit account fee authorization is enclosed herewith, bringing the period of response to July 22, 2005.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 8 of this paper.